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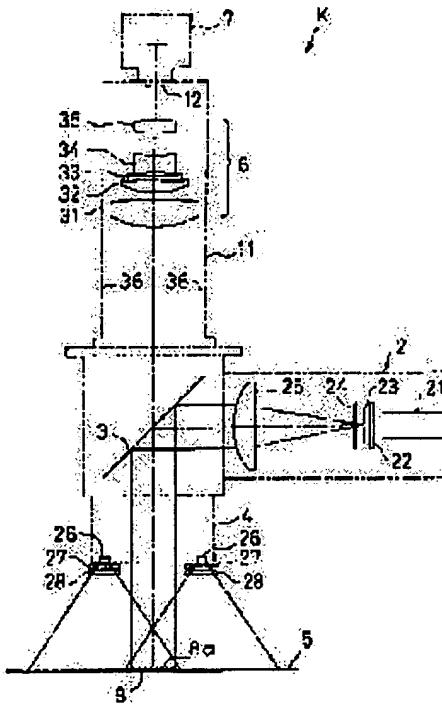
(21)Application number : **06-141118** (71)Applicant : **NEW KURIEISHIYON:KK**
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(54) OPTICAL SYSTEM FOR INSPECTION, AND INSPECTION APPARATUS

(57)Abstract:

PURPOSE: To extend the depth of a field in which a picture can be taken and provide an inspection apparatus in which an observation part can be included easily within a range of focuses.

CONSTITUTION: Regarding an optical system K for inspection in which parallel light rays are radiated to a specimen 8 by a radiation optical system K, the transmitted light rays or the reflected light rays are converged by an observation optical system 6, and observation of the specimen 8 is done by the observation part 7 in the rear side of the optical system 6, the optical system K for inspection is characteristically provided with the observation optical system K having a telecentric optical part 6 and an iris diaphragm 12 set in a rear image spatial focusing plane of the telecentric optical part 6 or near the plane.



LEGAL STATUS

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